| Notice of Allowability  | Application No.  | Applicant(s)                                       | Applicant(s)    |  |
|---|--|--|-----------------|--|
|   | 09/735,903   | FUJIWARA ET AL.                                    | FUJIWARA ET AL. |  |
|   | Examiner   | Art Unit   |                 |  |
|   | Fazli Erdem  | 2826   | M               |  |
| The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.  1. This communication is responsive to Amendment filed on 2/18/2005.  |  |  |                 |  |
| 2. The allowed claim(s) is/are <u>1-30</u> .  |  | NATHAN J. FLYNN                                    |                 |  |
| 3. The drawings filed on <u>14 December 2000</u> are accepted by the Examiner.  |  | SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2000 |                 |  |
| <ul> <li>4. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).</li> <li>a) All b) Some* c) None of the:</li> <li>1. Certified copies of the priority documents have been received.</li> <li>2. Certified copies of the priority documents have been received in Application No.</li> <li>3. Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).</li> <li>* Certified copies not received:</li> <li>Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.</li> <li>THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.</li> </ul>  |  |  |                 |  |
| 5. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.  |  |  |                 |  |
| <ul> <li>6. CORRECTED DRAWINGS ( as "replacement sheets") must be submitted. <ul> <li>(a) including changes required by the Notice of Draftsperson's Patent Drawing Review ( PTO-948) attached</li> <li>1) hereto or 2) to Paper No./Mail Date</li> <li>(b) including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date</li> <li>Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).</li> </ul> </li> <li>7. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.</li> </ul> |  |  |                 |  |
| <ul> <li>Attachment(s)</li> <li>1. ☑ Notice of References Cited (PTO-892)</li> <li>2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)</li> <li>3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/O Paper No./Mail Date</li></ul>   | 6. ☐ Interview Summa<br>Paper No./Mail D<br>8), 7. ☐ Examiner's Amen | )ate   |                 |  |

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## **DETAILED ACTION**

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## Allowable Subject Matter

1. Claims 1-30 allowed.

2. The following is an examiner's statement of reasons for allowance: Prior art failed to establish a nonvolatile semiconductor memory device comprising a substrate, a semiconductor forming region a first and second impurity regions, a gate insulating film stacked on the channel forming region comprised of a plurality of film, a gate electrode formed on the gate insulating film, a charge storing means which is formed in the gate insulating film dispersed in the plane facing the channel forming region and in the direction of thickness is injected with excited hot electrons in operation due to an electric field applied and were bottom insulating film positioned at the bottom in gate insulating film comprises a dielectric film that makes an energy barrier between the bottom insulating film and the substrate lower than that between silicon dioxide and silicon.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

## Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Fazli Erdem whose telephone number is (571) 272-1914. The examiner can normally be reached on M - F 8:00 - 5:00.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nathan Flynn can be reached on (571) 272-1915. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

FE

May 13, 2005